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Serial Number: 10/797,854

- 1) See attached printout of inventors listed in PALM
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Inventor Information for 10/797854

Inventor Name	City	State/Country
LIN, YU-LIANG	PINGTUNG	TAIWAN
DUNG, YU-LUNG	TAOYUAN	TAIWAN
HUANG, YUEH-LUNG	MIAOLI	TAIWAN
HUANG, CHEN-LIN	KAOHSIUNG	TAIWAN
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1	US	20070515	Fan speed	388/831	318/254;	Wu;
.	7218846	200,0010	control circuit		318/439;	Chia-
	B2		00224		318/599;	feng et
					388/805	al.
1	US	20070116	Fan control	318/471	318/254;	Wu;
1	7164249		device and		318/268;	Chia-
	B2		method		318/599;	Feng et .
					388/827	al.
1	US	20061024	Method to	422/100	257/E21.251;	Chang;
	7125521		solve		257/E23.179;	Chung-
	B2		alignment		422/101;	Long et
			mark blinded		422/67;	al.
			issues and		422/88;	
			technology for		73/863.32;	
			application of		73/864;	,
			semiconductor		73/864.01;	
		<u> </u>	etching at a		73/864.11	
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1	US	20060801	Advanced	451/5	257/E21.244;	Lin;
	7083495		process		257/E21.304;	Chun
	B2	ŀ	control		451/28;	Hsien et
			approach for		451/41;	al.
			Cu		451/8	
,			interconnect			
			wiring sheet			
			resistance			
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1	US .	20060502	Fan motor	318/268	318/471;	Lin; Yu-
	7038408		speed control		318/472;	liang et
	B2		circuit		318/473;	al.
					318/641;	
					388/934	
1	US	20050426	Method and	451/6	156/345.13;	Tsai;
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	B2		situ		451/53;	Ting et
	i		monitoring of		451/8	al.
			mixing ratio			.
			of high			
			selectivity			
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1	US	20050405	Application of	438/781	134/10;	Lin;
	6875709		a supercritical		134/12;	Chun-
	B2		CO2 system		257/E21.242;	Hsien et
			for curing low		257/E21.259;	al.
			k dielectric		257/E21.262;	
	J	1	materials	<u> </u>	257/E21.576;	l

					438/782; 438/793	-
1	US 6875285 B2	20050405	System and method for dampening high pressure impact on porous materials	134/2	134/25.4; 134/34; 134/36; 134/42; 257/E21.228; 257/E21.252	Wang; Ching- Ya et al.
1	US 6872127 B2	20050329	Polishing pad conditioning disks for chemical mechanical polisher	451/56	451/443	Lin; Yu- Liang et al.
1	US 6857942 B1	20050222	Apparatus and method for pre-conditioning a conditioning disc	451/56	451/443	Lin; Yu- Liang et al.
1	US 6746966 B1	20040608	Method to solve alignment mark blinded issues and a technology for application of semiconductor etching at a tiny area	438/734	257/E21.251; 257/E23.179; 438/425; 438/427; 438/430; 438/435; 438/692; 438/700; 438/704	Chang; Chung- Long et al.
1	US 6729935 B2	20040504	Method and system for insitu monitoring of mixing ratio of high selectivity slurry	451/6	250/574; 356/326; 356/328; 451/36; 451/446; 451/8	Tsai; Shang- Ting et al.
1	US D486906 S	20040217	Fan housing	D23/411		Xiao; Li- Hui et al.
1	 US D486569 S	20040210	Fan blade	D23/411		Chen; Heng-Yi et al.
1	 US	20040210	Fan blade	D23/370	,	Chen;

	D486568 S					Heng-Yi et al.
1	US D485613 S	20040120	Fan housing	D23/411		Xiao; Li- Hui et al
1	US 6406185 B1	20020618	Spindle seat in a fan	384/246	384/903	Lin; Yu- Liang
1	US 6341997 B1	20020129	Method for recycling a polishing pad conditioning disk	451/39	134/19; 134/22.18; 451/444; 451/53; 451/54; 451/56	Lin; Yu- Liang
1	US 6310453 B1	20011030	Drive circuit for a speed adjustable fan	318/445	318/268; 318/599; 318/799; 388/907.5	Lin; Yu Liang
1	US 6297608 B1	20011002	Drive circuit for a speed automatically adjusted fan	318/471	318/439	Lin; Yu Liang
1	US 6221160 B1	20010424	Method and apparatus for environmental control in a process chamber	118/326	118/DIG.7; 454/238; 454/239	Lin; Yu- Liang
1	US 6145702 A	20001114	Method and apparatus for adjusting minimum liquid level in a liquid supply bottle	222/64	141/95; 222/163; 248/132	Lin; Yu- Liang et al.
1	US 6142195 A	20001107	Quick release container clamp	141/383	141/369; 141/372; 141/375; 141/386	Lin; Yu- Liang
1	US 6049183 A	20000411	Brushless direct current fan	318/434	318/473; 318/490	Lin; Yu Liang